Inventor:

Fernando Gonzalez

Title:

Methods of Forming Semiconductor Constructions

Assignee:

Micron Technology, Inc.

## INFORMATION DISCLOSURE STATEMENT

## PURSUANT TO 37 C.F.R. §§ 1.56, 1.97 AND 1.98

In compliance with 37 C.F.R. §§ 1.56, 1.97 and 1.98, your attention is directed to the United States patents and other references listed on the attached Form PTO-1449. No admission is made regarding whether all the submitted references are prior art.

The listed references were cited by, or submitted to, the Office in the parent, co-pending application of the above-identified application. The above-identified application is a continuation application of co-pending application Serial No. 10/271,888, filed October 15, 2002. Such prior disclosure is sufficient for the above-identified application as far as copies of the references are concerned. 37 C.F.R. § 1.98(d) and MPEP § 609(2).

Citation of these references is respectfully requested.

Datad:

Bv:

David G. Latwesen, Ph.D.

Respectfully submitted,

Reg. No. 38,533

Form PTO-144	19	U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE					ATTY. DOCKET N MI22-2383	Prio. 10/2	Priority SERIAL NO. 10/271,888			
		LIST	T OF ART CITED I	APPLICANT Fernando Gonzalez								
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EXAMINER DATE CONSIDERED												
*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.												